

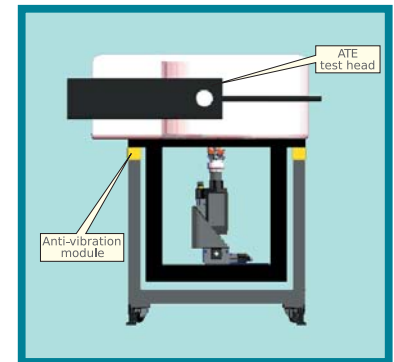
SEMICAPS 4000 CONFIGURATION

INVERTED ANALYTICAL AND TESTER-DOCKED SYSTEM

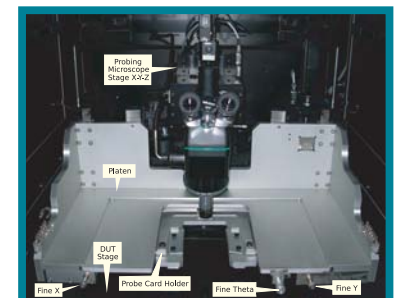


Features

- Analytical configuration or ATE docked
- 300mm wafer stage including auto-lock compatible with Production Probe Cards and manipulators
- Docks easily to Tester or Probe Station
- High resolution stage with 20nm resolution and 0.5µm repeatability
- Centric and Aplanatic Refractive Solid Immersion Lens (RSIL) option
- CAD interface option
- Compatible with thermal management solutions
- Techniques include:
 - Laser Timing Probe (LTP) with frequency mapping for locating signals
 - Scanning Optical Microscopy (SOM) with best-in-class sensitivity for static and dynamic laser induced techniques
 - Photon Emission Microscopy (PEM) with LN2-free, low noise InGaAs or Si-CCD camera
 - Thermal Microscopy (THM) with InSb camera



ATE-Docked



300mm Probe Station